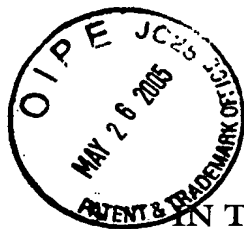


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Docket No.: M4065.0227/P227-A  
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:  
Tongbi Jiang et al.

Application No.: 09/998,165

Confirmation No.: 7636

Filed: December 3, 2001

Art Unit: 2829

For: METHOD AND APPARATUS FOR  
REDUCING SUBSTRATE BIAS VOLTAGE  
DROP

Examiner: E. T. Pert

STATUS INQUIRY

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

It is respectfully requested that the attorney named below be advised of the status of the above-identified application. Please advise us of when we might expect to receive an Office Action from the Patent and Trademark Office.

Dated: May 26, 2005

Respectfully submitted,

By

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